

	U	Doc ID	Issue Date	Pages	Title	Current OR	Current XRef	Retrieval C	Inventor	S	C	P	2	3	In
1	<input type="checkbox"/>	US 20040130726 A1	20040708	10	Method for determining layer thickness ranges	356/504			Mikkelsen, Hakon et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	US
2	<input type="checkbox"/>	US 20040004724 A1	20040108		Spin etcher with thickness measuring system	356/504	257/821.53		Kim, Chung-Sik et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	
3	<input type="checkbox"/>	US 20030147085 A1	20030807		Method for the determination of layer thicknesses	356/504			Mikkelsen, Hakon et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	
4	<input type="checkbox"/>	US 20030133127 A1	20030717		Method for monitoring the rate of etching of a	356/504			Zaidi, Shoaib Hasan et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	
5	<input type="checkbox"/>	US 20030112446 A1	20030619		Method for biomolecular sensing and system thereof	356/504			Miller, Benjamin et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	
6	<input type="checkbox"/>	US 20030090676 A1	20030515		In-situ film thickness measurement using spectral	356/504	257/821.528; 257/821.53		Goebel, Andreas et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	
7	<input type="checkbox"/>	US 20020163649 A1	20021107	42	Film thickness measuring method and apparatus, and	356/504			Hirose, Takenori et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	US
8	<input type="checkbox"/>	US 20020113971 A1	20020822		Method for measuring characteristics, especially	356/450	356/504; 356/519		Jettler, Jorg-Thomas et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	
9	<input type="checkbox"/>	US 6826511 B2	20041130		Method and apparatus for the determination of layer	702/172	356/504; 702/159;		Mikkelsen, Hakon et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	
10	<input type="checkbox"/>	US 6806970 B2	20041019	20	Thin film thickness measuring method and	356/630	356/503; 356/504;		Hirose, Takenori et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	US
11	<input type="checkbox"/>	US 6801322 B2	20041005		Method and apparatus for IN SITU measuring a required	356/504			Mautz, Karl	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	